

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Takashi NISHIKAWA

Serial No.: 10/019,540

Filed: January 3, 2002

For: LAYERED STRUCTURE, METHOD FOR MANUFACTURING THE SAME, AND
SEMICONDUCTOR ELEMENT

Group Art Unit: 2815

Examiner: Bradley E. BAUMEISTER

10/ Elect
G. Stay
7-3-03

RESPONSE TO RESTRICTION REQUIREMENT

Mail Stop Restriction Requirement
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Noting the Office Action of March 19, 2003 wherein restriction has been required, Applicant(s) hereby elect Group II (claims 5-13, drawn to a method of making a semiconductor structure) for prosecution in the above-identified application.

To the extent necessary, a petition for an extension of time under 37 C.F.R. 1.136 is hereby made. Please charge any shortage in fees due in connection with the filing of this paper, including extension of time fees, to Deposit Account 500417 and please credit any excess fees to such deposit account.

Respectfully submitted,

McDERMOTT, WILL & EMERY

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